

**In the Abstract:**

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**ABSTRACT OF THE DISCLOSURE**

The method of making invention provides a high quality-identifiable fluoride crystalline optical microlithography lens element blank includes crystallizing a fluoride crystalline member with a dimension  $\geq 200$  nm from a melt, annealing the fluoride crystalline member and qualifying the resulting member for use as an optical microlithography lens element blank for formation into an lens element of a microlithography system. The highly qualified fluoride crystalline characteristics of the fluoride optical lithography lens blank ensure its beneficial performance in the demanding microlithography manufacturing regime which utilizes high energy short wavelength ultraviolet laser sources. The fluoride crystalline optical lithography lens element blanks have are comprised of multiple adjoining abutting crystalline subgrains with low boundary angles. The crystalline members made by the method are qualified for use as lens element blanks by a testing method including measuring their absorption spectra at 200 to 220 nm to determine absorbance at 205 nm and/or by making measurements of radiation diffracted by them.